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DELUER  
10-18-01PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/821,695  
Filing Date: March 29, 2001  
Applicant: Mikio SAITO  
Group Art Unit: N/A  
Examiner: Not Yet Assigned  
Title: METHOD AND APPARATUS FOR EXAMINING  
THROUGH HOLES  
Attorney Docket: 9319S-000195

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Hon. Commissioner of Patents and Trademarks  
Washington, D.C. 20231

PRELIMINARY AMENDMENT

Sir:

Prior to the examination of this application, please amend it as follows:

IN THE SPECIFICATION

A1 [0002] Conventionally, examinations of through holes each having a diameter of several ten ~ several hundred micron millimeters are generally conducted to check if a correct number of the through holes are opened, if the sizes of the through holes are uniform, if any foreign matters are present in the through holes, and the like. Optical methods are generally conducted for such examinations. For example, an area sensor camera is used to photograph an examining surface of a work piece where through holes are formed, and an image processing apparatus is used to compare the